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Active microneedle actuated by thermopneumatic force

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ABSTRACT

This paper presents a novel movable microneedle that becomes active when necessary to use. Conventional researches have been focused on the fabrication of microneedles and the interface with fluidic chip [1,2]. Therefore, we proposed an active microneedle to sample body fluids or deliver drugs in a controlled amount by actuating the needles. This allows us to keep the needles in operation only when necessary so that both the body skin and the needles can be protected from undesirable external disturbance while no operation.

Key Words : Thermopneumatic (), Active (), Microneedle ().

1.

2.

가
가

2.1

Figure 1

6

가
layer, needle layer
supporting layer
channel layer,
chamber layer, heater
가 substrate layer
needle layer substrate layer layer
flexible PDMS

[1,2],

interface

가

가

2.2

PDMS (Sylgard 184, Dow corning)

PDMS solution

10:1

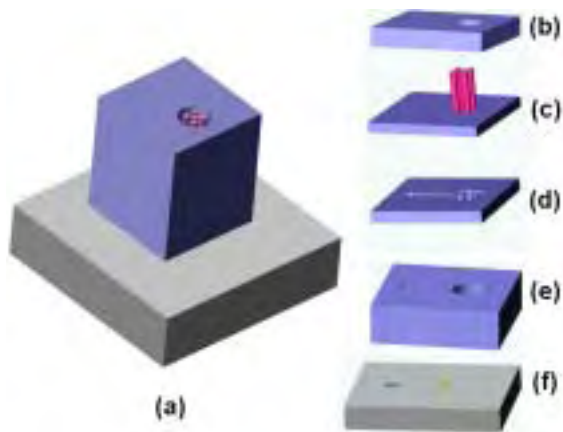


Fig. 1. Schematic configuration of the proposed microneedle and fabrication sequence (a) three dimensional view of the proposed microneedle, (b) PDMS spincoating and punch out, (c) needle fabrication, (d) SU-8 pattern and PDMS molding, (e) PDMS spincoating and punch out, and (f) Ti/Au pattern on the glass substrate using lift off process.

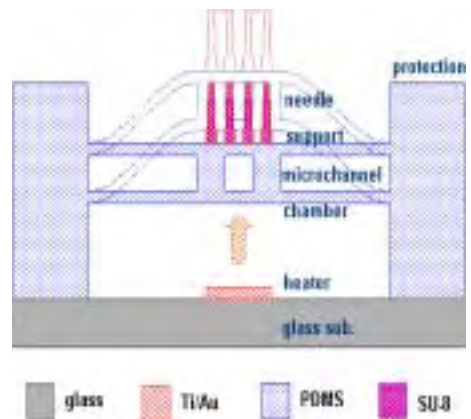


Fig. 2. Cross-sectional view and working principle of the proposed microneedle.

vacuum desiccator

Fig.1(b),(e) PDMS spin coating

chamber Fig.1(c)
 microneedle supporting layer
 needle PDMS spin coating
 Fig.1(d) channel layer SU-8(Micro chem.) spin coating photo lithography
 PDMS Fig.1(f) heater 가 substrate layer heater
 Ti/Au liftoff process
 oxygen plasma

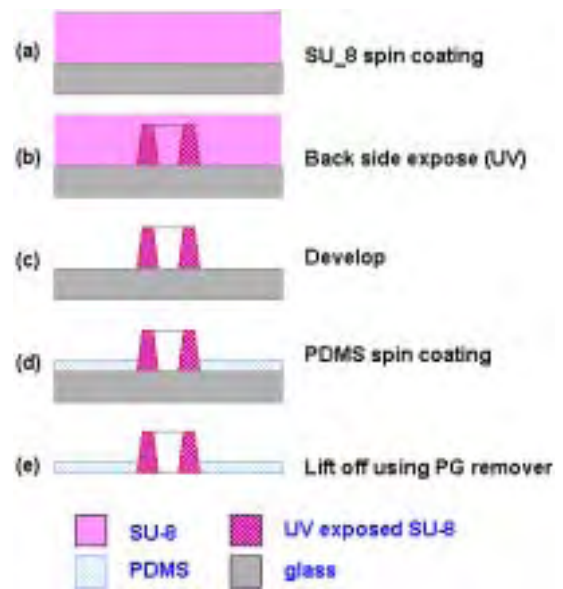


Fig. 3 Fabrication process of the needle layer.

3.

3.1

Figure 3

SU-8 spin coating
 back side exposure
 SU-8 developer develop tapered
 layer Supporting
 PDMS spin coating
 PG remover(Micro chem.)
 supporting layer 가

2.3

Figure 2 cross-sectional
 heater
 가 chamber
 channel support layer
 needle

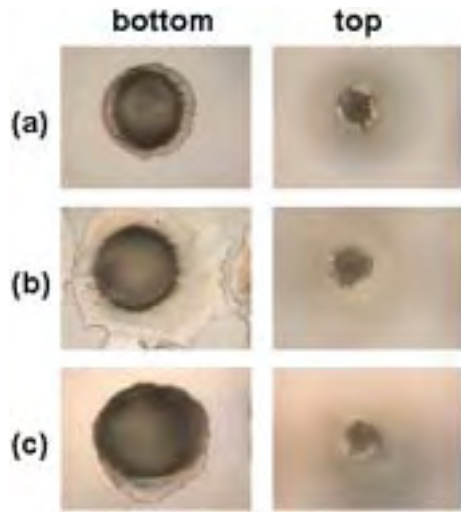


Fig. 4. Microscopic bottom and top view of the fabricated needle processed at the different exposure time for SU-8 (UV intensity 25 mW/cm²); (a) 2 min, (b) 4 min, and (c) 6 min.

Table 1. microneedle dimension

Exposure	Inner diameter	Thickness	Bottom diameter	Needle length
2 min	116 μm	16 μm	178 μm	415 μm
4 min	112 μm	11.5 μm	205 μm	463 μm
6 min	83.8 μm	7.35 μm	214 μm	588 μm

3.2

Figure 4 UV exposure time microscopic

Exposure time 2, 4, 6

Table 1

UV exposure time 가

가

160 μm 가

backside exposure

Figure 5 SEM UV exposure time 410 μm, 470 μm, 580 μm

4.

Membrane membrane (1) chamber

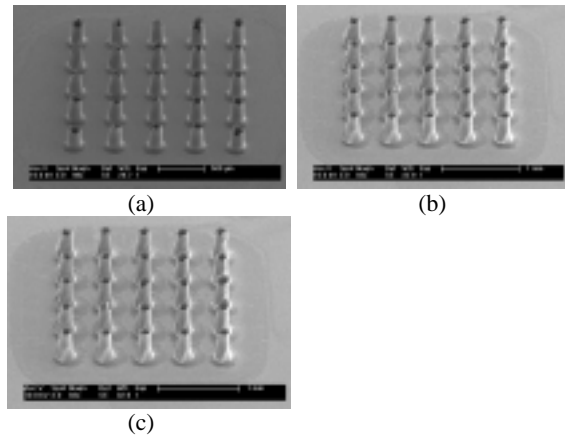


Fig. 5. SEM pictures of the array of microneedles processed at the different exposure time for SU-8; (a) 2 min, (b) 4 min, and (c) 6 min.

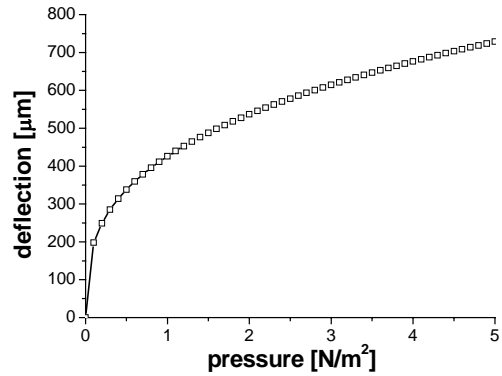


Fig. 6. Theoretical deflection of the PDMS membrane as a function of an input pressure.

plate ($w_0 \gg h$) [3].

$$W_o = 0.662a^3 \sqrt{\frac{Pa}{Eh}} \quad (1)$$

w_o : maximum deflection a : radius h : thickness p : pressure E : Young's modulus

Figure 6.

Figure 7 membrane 가 가

4.

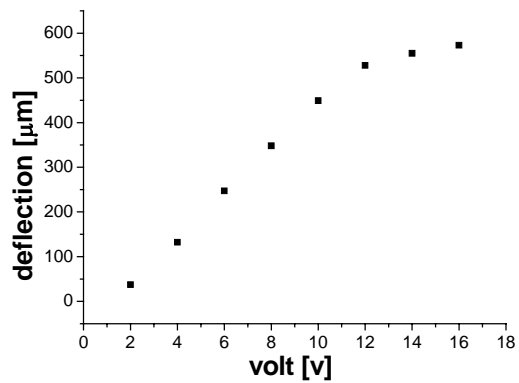


Fig. 7. Measured deflection of the PDMS membrane as a function of an input voltage.

가 . PDMS membrane
250 μm

(MOST) “Development of LoC
technology for MDSN (multi distributed sensor network)”

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